## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No
Filing Date November 2, 2000
Inventor Segal et al.
Assignee Honeywell International Inc.
Group Art Unit
Examiner Ip, Sikyin
Attorney's Docket No 30-5076(4015)
Title: Physical Vapor Deposition Targets and Methods of Fabricating Metallic Materials

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

Citation of these references is respectfully requested.

Respectfully submitted,

Date: August 29, 2004

Jennifer J. Taylor, Ph.D.

Reg. No. 48,711

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

DATE CONSIDERED

EXAMINER

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						APPLICANT Vladimir Segal et al.					
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)											
	AK		S. Ferrasse et al., "ECAE Targets with Sub-Micron Grain Structures Improve Sputtering Performance and Cost-of-Ownership", Semicond Manufacturing, Vol. 4, Issue 10, October 2003, pp. 76-92.							onductor	
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			Metallurgical and Materials Transactions A, Volume 28A, April 1997, pp. 1047-1057.								
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